

Jaume Esteve

List of Publications by Year in descending order

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218
papers

3,897
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117625

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docs citations

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times ranked

3600
citing authors

#	ARTICLE	IF	CITATIONS
1	Biocompatibility and Electrical Stimulation of Skeletal and Smooth Muscle Cells Cultured on Piezoelectric Nanogenerators. <i>International Journal of Molecular Sciences</i> , 2022, 23, 432.	4.1	6
2	Microdevices for Cell Stimulation: Integrated Zinc Oxide Piezoelectric Nanostructures in Silicon Microparticles. , 2021, , .		1
3	ZnO Nanosheet-Coated TiZrPdSiNb Alloy as a Piezoelectric Hybrid Material for Self-Stimulating Orthopedic Implants. <i>Biomedicines</i> , 2021, 9, 352.	3.2	9
4	Self-activated microbatteries to promote cell death through local electrical stimulation. <i>Nano Energy</i> , 2021, 83, 105852.	16.0	7
5	Development of Hybrid Piezoelectric Microdevices for Bioapplications. , 2021, , .		0
6	Non-linear nanoscale piezoresponse of single ZnO nanowires affected by piezotronic effect. <i>Nanotechnology</i> , 2021, 32, 025202.	2.6	12
7	Internalization and Viability Studies of Suspended Nanowire Silicon Chips in HeLa Cells. <i>Nanomaterials</i> , 2020, 10, 893.	4.1	3
8	Optimization of a Piezoelectric Energy Harvester and Design of a Charge Pump Converter for CMOS-MEMS Monolithic Integration. <i>Sensors</i> , 2019, 19, 1895.	3.8	18
9	Permanently hydrophilic, piezoelectric PVDF nanofibrous scaffolds promoting unaided electromechanical stimulation on osteoblasts. <i>Nanoscale</i> , 2019, 11, 8906-8917.	5.6	109
10	Role of aluminum and HMTA in the hydrothermal synthesis of two-dimensional n-doped ZnO nanosheets. <i>Nano Energy</i> , 2019, 60, 817-826.	16.0	33
11	Towards the Monolithic Integration of Converter Circuitry and Piezoelectric MEMS Energy Harvesters. <i>Proceedings (mdpi)</i> , 2018, 2, .	0.2	2
12	Electrical stimulation of cells through photovoltaic microcell arrays. <i>Nano Energy</i> , 2018, 51, 571-578.	16.0	13
13	Improving Morphological Quality and Uniformity of Hydrothermally Grown ZnO Nanowires by Surface Activation of Catalyst Layer. <i>Nanoscale Research Letters</i> , 2017, 12, 51.	5.7	16
14	Highly Anisotropic Suspended Planar Array Chips with Multidimensional Submicrometric Biomolecular Patterns. <i>Advanced Functional Materials</i> , 2017, 27, 1605912.	14.9	13
15	Development of piezoelectric nanostructures for cell stimulation. , 2017, , .		1
16	Electromechanical Nanogenerator Cell Interaction Modulates Cell Activity. <i>Advanced Materials</i> , 2017, 29, 1605048.	21.0	116
17	From materials to devices: Bottom-up integration of nanomaterials onto silicon microstructures for thermoelectric and piezoelectric applications. , 2017, , .		0
18	Suspended Silicon Microphotodiodes for Electrochemical and Biological Applications. <i>Small</i> , 2017, 13, 1701920.	10.0	7

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19	Heat-controlled micropillar array device for microsystems technology. <i>Soft Matter</i> , 2017, 13, 7264-7272.	2.7	11
20	Study of Galfenol direct cytotoxicity and remote microactuation in cells. <i>Biomaterials</i> , 2017, 139, 67-74.	11.4	11
21	Suspended Planar Array Chips for Molecular Multiplexing at the Microscale. <i>Advanced Materials</i> , 2016, 28, 1449-1454.	21.0	20
22	Selective Area Growth of High-Quality ZnO Nanosheets Assisted by Patternable AlN Seed Layer for Wafer-Level Integration. <i>Crystal Growth and Design</i> , 2016, 16, 5059-5066.	3.0	19
23	Integration of Liquid-Crystalline Elastomers in MEMS/MOEMS. , 2016, , 553-582.		6
24	Silicon-nanowire based attachment of silicon chips for mouse embryo labelling. <i>Lab on A Chip</i> , 2015, 15, 1508-1514.	6.0	5
25	Combination of PDMS microfilters and micromixers based on flexible thermoplastic films for size sorting and mixing of microparticles. <i>Journal of Applied Polymer Science</i> , 2015, 132, .	2.6	4
26	SiNERGY, a project on energy harvesting and microstorage empowered by Silicon technologies. , 2015, , .		0
27	Nanoscale imaging of buried topological defects with quantitative X-ray magnetic microscopy. <i>Nature Communications</i> , 2015, 6, 8196.	12.8	61
28	Technological development of intracellular polysiliconâ€“chromiumâ€“gold chips for orthogonal chemical functionalization. <i>Sensors and Actuators B: Chemical</i> , 2015, 209, 212-224.	7.8	7
29	Charge storage and retention in electret dielectric layers for energy harvesting applications. , 2014, , .		0
30	Barcode tagging of human oocytes and embryos to prevent mix-ups in assisted reproduction technologies. <i>Human Reproduction</i> , 2014, 29, 18-28.	0.9	22
31	Gasâ€“Pressure Moldingâ€“Based Fabrication of Smart Actuators from Nematic Liquidâ€“Crystalline Elastomer. <i>Macromolecular Materials and Engineering</i> , 2014, 299, 1163-1169.	3.6	5
32	Integration of PDMS microfilters and micromixers bonded onto APTES-functionalized polymeric films for size sorting and mixing of microparticles. , 2014, , .		0
33	Tactile device based on opto-mechanical actuation of liquid crystal elastomers. <i>Sensors and Actuators A: Physical</i> , 2014, 208, 104-112.	4.1	72
34	Tactile Acuity Charts: A Reliable Measure of Spatial Acuity. <i>PLoS ONE</i> , 2014, 9, e87384.	2.5	24
35	Silicon chips detect intracellular pressure changes in living cells. <i>Nature Nanotechnology</i> , 2013, 8, 517-521.	31.5	68
36	Liquid-crystalline elastomer micropillar array for haptic actuation. <i>Journal of Materials Chemistry C</i> , 2013, 1, 5183.	5.5	58

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37	Polymer micromixers bonded to thermoplastic films combining soft lithography with plasma and apes treatment processes. <i>Journal of Polymer Science Part A</i> , 2013, 51, 59-70.	2.3	12
38	Nanocomposite photoactuators based on an ethylene vinyl acetate copolymer filled with carbon nanotubes. <i>Sensors and Actuators B: Chemical</i> , 2013, 186, 701-710.	7.8	29
39	Integration of NEMS resonators in a 65nm CMOS technology. <i>Microelectronic Engineering</i> , 2013, 110, 246-249.	2.4	29
40	Sensitivity of thin-film bulk acoustic resonators (FBAR) to localized mechanical forces. <i>Journal of Micromechanics and Microengineering</i> , 2013, 23, 065024.	2.6	4
41	Nematic opto-mechanical actuators for the fabrication of refreshable tactile systems. , 2013, , .		1
42	Electrospun nanobridges towards self-heated gas sensors with enhanced sensitivity. <i>Journal of Physics: Conference Series</i> , 2013, 421, 012002.	0.4	1
43	Novel optimized design of a piezoelectric energy harvester in a package for low amplitude vibrations. <i>Journal of Physics: Conference Series</i> , 2013, 476, 012042.	0.4	4
44	Batch fabrication of optical actuators using nanotube-elastomer composites towards refreshable Braille displays. <i>Journal of Micromechanics and Microengineering</i> , 2012, 22, 075009.	2.6	72
45	Thin-Film Piezoelectric MEMS Transducer Suitable for Middle-Ear Audio Prostheses. <i>Journal of Microelectromechanical Systems</i> , 2012, 21, 1452-1463.	2.5	9
46	Stress mapping on the porous silicon microcapsules by Raman microscopy. <i>Microelectronic Engineering</i> , 2012, 98, 488-491.	2.4	17
47	Integration of piezoelectric energy scavengers with FBAR resonators for the miniaturization of autonomous wireless sensors nodes. , 2012, , .		2
48	Geochemical and mineralogical characterization of surficial sediments from the Northern Rias: Implications for sediment provenance and impact of the source rocks. <i>Marine Geology</i> , 2012, 291-294, 63-72.	2.1	20
49	In-parallel maskless fabrication of nanowire-based device array. , 2011, , .		0
50	Electromagnetic harvester device for scavenging ambient mechanical energy with slow, variable, and randomness nature. , 2011, , .		2
51	Chemical Functionalization of Polysilicon Microparticles for Single-Cell Studies. <i>Langmuir</i> , 2011, 27, 8302-8308.	3.5	7
52	Bending kinetics of a photo-actuating nematic elastomer cantilever. <i>Applied Physics Letters</i> , 2011, 99, .	3.3	58
53	Front Matter: Volume 8107. <i>Proceedings of SPIE</i> , 2011, , .	0.8	2
54	Study of LCE nanocomposites through electron microscopy. , 2011, , .		0

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55	Education and dissemination strategies of photoactuation as a novel phenomenon. Proceedings of SPIE, 2011, , .	0.8	2
56	Opto-mechanical parameters of liquid crystals elastomers with carbon nanotubes. Proceedings of SPIE, 2011, , .	0.8	5
57	Nano opto-mechanical systems (NOMS) as a proposal for tactile displays. Proceedings of SPIE, 2011, , .	0.8	6
58	Mechanical modeling of thermally actuated LCE-CNT composite. Proceedings of SPIE, 2011, , .	0.8	0
59	DRIE based technology for 3D silicon barcodes fabrication. Sensors and Actuators B: Chemical, 2011, 154, 181-184.	7.8	2
60	Directed Fracture for the Fabrication of Free-standing Multilayered Submicrometer Structures. Small, 2011, 7, 558-562.	10.0	1
61	Localised Actuation in Composites Containing Carbon Nanotubes and Liquid Crystalline Elastomers. Macromolecular Rapid Communications, 2011, 32, 1953-1959.	3.9	66
62	A novel embryo identification system by direct tagging of mouse embryos using silicon-based barcodes. Human Reproduction, 2011, 26, 96-105.	0.9	26
63	Light-actuated CNT-doped elastomer blisters towards braille dots. , 2011, , .		4
64	Nanomagnets with high shape anisotropy and strong crystalline anisotropy: perspectives on magnetic force microscopy. Nanotechnology, 2011, 22, 505301.	2.6	17
65	Micro-barcodes for biological applications. , 2011, , .		0
66	Microstamped opto-mechanical actuator for tactile displays. , 2011, , .		3
67	Focus ion beam micromachined glass pipettes for cell microinjection. Biomedical Microdevices, 2010, 12, 311-316.	2.8	2
68	Internalization and cytotoxicity analysis of silicon-based microparticles in macrophages and embryos. Biomedical Microdevices, 2010, 12, 371-379.	2.8	22
69	In situ MEMS gradiometer with nanometer-resolution optical detection system. Sensors and Actuators A: Physical, 2010, 159, 33-40.	4.1	2
70	Design and characterization of a magnetic digital flow regulator. Sensors and Actuators A: Physical, 2010, 162, 107-115.	4.1	10
71	Resonance frequency dependence on out-of-plane forces for square silicon membranes: Applications to a MEMS gradiometer. Sensors and Actuators A: Physical, 2010, 163, 75-81.	4.1	6
72	Intracellular Silicon Chips in Living Cells. Small, 2010, 6, 499-502.	10.0	35

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73	Zero-level packaging of MEMS in standard CMOS technology. Journal of Micromechanics and Microengineering, 2010, 20, 064009.	2.6	16
74	Comparative performance of static-mode ferrous MEMS gradiometers fabricated by a three-step DRIE process. Journal of Micromechanics and Microengineering, 2010, 20, 075006.	2.6	0
75	Electron microscopy of polymer-carbon nanotubes composites. , 2010, , .		0
76	Nanomagnet fabrication on FBAR for magnetic sensor applications. , 2009, , .		3
77	Implementation of ion-beam techniques in microsystems manufacturing: opportunities in cell biology. Proceedings of SPIE, 2009, , .	0.8	1
78	Sharpened transparent micronozzle fabrication for cell membrane piercing. Proceedings of SPIE, 2009, , .	0.8	1
79	Versatile micropipette technology based on deep reactive ion etching and anodic bonding for biological applications. Journal of Micromechanics and Microengineering, 2009, 19, 105013.	2.6	14
80	Reduction of droplet-size dispersion in parallel flow-focusing microdevices using a passive method. Journal of Micromechanics and Microengineering, 2009, 19, 045029.	2.6	10
81	Linear and non-linear behavior of mechanical resonators for optimized inertial electromagnetic microgenerators. Microsystem Technologies, 2009, 15, 1217-1223.	2.0	16
82	DRIE based technology for 3D silicon barcodes fabrication. Procedia Chemistry, 2009, 1, 800-803.	0.7	1
83	Intracellular Polysilicon Barcodes for Cell Tracking. Small, 2009, 5, 2433-2439.	10.0	43
84	High-frequency sensor technologies for inertial force detection based on thin-film bulk acoustic wave resonators (FBAR). Microelectronic Engineering, 2009, 86, 1254-1257.	2.4	16
85	Analytical and Finite-Element Modeling of Localized-Mass Sensitivity of Thin-Film Bulk Acoustic-Wave Resonators (FBAR). IEEE Sensors Journal, 2009, 9, 892-901.	4.7	12
86	Focused-Ion-Beam-Assisted Magnet Fabrication and Manipulation for Magnetic Field Detection Applications. ACS Applied Materials & Interfaces, 2009, 1, 527-531.	8.0	5
87	Design and fabrication of Si technology microgenerators for vibrational energy scavenging. , 2009, , .		0
88	Microneedles electrodes for living cells. , 2009, , .		0
89	A New Single-Sensor Magnetic Field Gradiometer. Sensor Letters, 2009, 7, 563-570.	0.4	11
90	Design and implementation of mechanical resonators for optimized inertial electromagnetic microgenerators. Microsystem Technologies, 2008, 14, 653-658.	2.0	42

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91	Automated on-wafer extraction of equivalent-circuit parameters in thin-film bulk acoustic wave resonators and substrate. <i>Microwave and Optical Technology Letters</i> , 2008, 50, 4-7.	1.4	3
92	Localized-mass detection based on thin-film bulk acoustic wave resonators (FBAR): Area and mass location aspects. <i>Sensors and Actuators A: Physical</i> , 2008, 142, 322-328.	4.1	22
93	Design, fabrication and characterization of an externally actuated ON/OFF microvalve. <i>Sensors and Actuators A: Physical</i> , 2008, 147, 600-606.	4.1	31
94	Analytical and finite-element modeling of a localized-mass sensor. , 2008, , .		0
95	Monolithic CMOS MEMS Oscillator Circuit for Sensing in the Attogram Range. <i>IEEE Electron Device Letters</i> , 2008, 29, 146-148.	3.9	117
96	Linear and non linear behavior of mechanical resonators for optimized inertial electromagnetic microgenerators. , 2008, , .		2
97	Focused ion beam-assisted technology in sub-picolitre micro-dispenser fabrication. <i>Journal of Micromechanics and Microengineering</i> , 2008, 18, 075021.	2.6	11
98	Thin-Film Bulk Acoustic Wave Resonator Floating Above CMOS Substrate. <i>IEEE Electron Device Letters</i> , 2008, 29, 28-30.	3.9	9
99	12E-1 Accelerometer Based on Thin-Film Bulk Acoustic Wave Resonators. <i>Proceedings IEEE Ultrasonics Symposium</i> , 2007, , .	0.0	2
100	Fully integrated MIXLER based on VHF CMOS-MEMS clamped-clamped beam resonator. <i>Electronics Letters</i> , 2007, 43, 452.	1.0	24
101	Instantaneous de-embedding of the on-wafer equivalent-circuit parameters of acoustic resonator (FBAR) for integrated circuit applications. , 2007, , .		1
102	Magnetically actuated microvalve for disposable drug infusor. , 2007, , .		2
103	Monolithic mass sensor fabricated using a conventional technology with attogram resolution in air conditions. <i>Applied Physics Letters</i> , 2007, 91, .	3.3	58
104	Silicon Microdevice for Emulsion Production Using Three-Dimensional Flow Focusing. <i>Journal of Microelectromechanical Systems</i> , 2007, 16, 1201-1208.	2.5	18
105	Fabrication and Test of 3C-SiC Electrostatic Resonators. <i>Materials Science Forum</i> , 2007, 556-557, 949-952.	0.3	0
106	Design and implementation of mechanical resonators for optimized inertial electromagnetic microgenerators. , 2007, , .		1
107	Towards a Microsystem of Multiple Production of Micro-Drops Manufactured on Silicon. , 2007, , .		0
108	Time-Resolved Evaporation Rate of Attoliter Glycerine Drops Using On-Chip CMOS Mass Sensors Based on Resonant Silicon Micro Cantilevers. <i>IEEE Nanotechnology Magazine</i> , 2007, 6, 509-512.	2.0	9

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109	Monolithic 0.35- μm CMOS Cantilever for Mass Sensing in the Attogram Range with Self-Excitation. , 2007, , .		1
110	Automated on-wafer characterization in micro-machined resonators: towards an integrated test vehicle for bulk acoustic wave resonators (FBAR). , 2007, , .		0
111	Focused-ion-beam-assisted tuning of thin-film bulk acoustic wave resonators (FBARs). Journal of Micromechanics and Microengineering, 2007, 17, 2380-2389.	2.6	9
112	Nanometer scale gaps for capacitive transduction improvement on RF-MEMS resonators. Microelectronic Engineering, 2007, 84, 1384-1387.	2.4	7
113	Fabrication of nanogaps for MEMS prototyping using focused ion beam as a lithographic tool and reactive ion etching pattern transfer. Microelectronic Engineering, 2007, 84, 1215-1218.	2.4	7
114	Electrical detection of multiple resonant modes in a CMOS-MEMS cantilever. Microelectronic Engineering, 2007, 84, 1374-1378.	2.4	4
115	Parasitic effect on silicon MEMS resonator model parameters. Microelectronic Engineering, 2007, 84, 1363-1368.	2.4	19
116	Microinductive Signal Conditioning With Resonant Differential Filters: High-Sensitivity Biodetection Applications. IEEE Transactions on Instrumentation and Measurement, 2007, 56, 1590-1595.	4.7	9
117	Vibrational energy scavenging with Si technology electromagnetic inertial microgenerators. Microsystem Technologies, 2007, 13, 1655-1661.	2.0	50
118	P2K-2 Sensitivity Considerations in Localized Mass Detection Based on Thin-Film Bulk Acoustic Wave Resonators. , 2006, , .		2
119	Localized and distributed mass detectors with high sensitivity based on thin-film bulk acoustic resonators. Applied Physics Letters, 2006, 89, 033507.	3.3	45
120	Integrated CMOS-MEMS with on-chip readout electronics for high-frequency applications. IEEE Electron Device Letters, 2006, 27, 495-497.	3.9	74
121	Molybdenum alloy electrodeposits for magnetic actuation. Electrochimica Acta, 2006, 51, 3214-3222.	5.2	30
122	Si technology based microinductive devices for biodetection applications. Sensors and Actuators A: Physical, 2006, 132, 499-505.	4.1	10
123	System on chip mass sensor based on polysilicon cantilevers arrays for multiple detection. Sensors and Actuators A: Physical, 2006, 132, 154-164.	4.1	38
124	A platform for monolithic CMOS-MEMS integration on SOI wafers. Journal of Micromechanics and Microengineering, 2006, 16, 2203-2210.	2.6	22
125	CMOS-SOI platform for monolithic integration of crystalline silicon MEMS. Electronics Letters, 2006, 42, 800.	1.0	1
126	<title>Band-pass transimpedance read-out circuit for UHF MEMS resonator applications</title>. , 2005, , .		0

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127	<title>Integrable silicon microsystem for three-dimensional flow focusing</title>. , 2005, , .		0
128	<title>MEMS with integrated CMOS read-out circuit based on sub-micrometric cantilevers array for multiple sensing (Invited Paper)</title>. , 2005, , .		0
129	<title>Large-signal model of a resonating cantilever-based transducer for system level electrical simulation</title>. , 2005, , .		1
130	Electrochemical deposition of Cu and Ni/Cu multilayers in Si Microsystem Technologies. Sensors and Actuators A: Physical, 2005, 123-124, 633-639.	4.1	19
131	Resonators with integrated CMOS circuitry for mass sensing applications, fabricated by electron beam lithography. Nanotechnology, 2005, 16, 98-102.	2.6	39
132	<title>CMOS degradation effects due to electron beam lithography in smart NEMS fabrication</title>. , 2005, 5836, 667.		5
133	Design, fabrication, and characterization of a submicroelectromechanical resonator with monolithically integrated CMOS readout circuit. Journal of Microelectromechanical Systems, 2005, 14, 508-519.	2.5	59
134	Piezoresistive accelerometers for MCM-package - Part II:The packaging. Journal of Microelectromechanical Systems, 2005, 14, 806-811.	2.5	11
135	Ultrasensitive mass sensor fully integrated with complementary metal-oxide-semiconductor circuitry. Applied Physics Letters, 2005, 87, 043507.	3.3	105
136	Fully CMOS integrated low voltage 100 MHz MEMS resonator. Electronics Letters, 2005, 41, 1327.	1.0	17
137	AFM lithography for the definition of nanometre scale gaps: application to the fabrication of a cantilever-based sensor with electrochemical current detection. Nanotechnology, 2004, 15, 771-776.	2.6	21
138	Technological aspects on the fabrication of silicon-based optical accelerometer with ARROW structures. Sensors and Actuators A: Physical, 2004, 110, 395-400.	4.1	9
139	BESOI-Based Integrated Optical Silicon Accelerometer. Journal of Microelectromechanical Systems, 2004, 13, 355-364.	2.5	37
140	Characterization and Passivation Effects of an Optical Accelerometer Based on Antiresonant Waveguides. IEEE Photonics Technology Letters, 2004, 16, 233-235.	2.5	10
141	Fabrication of cantilever based mass sensors integrated with CMOS using direct write laser lithography on resist. Nanotechnology, 2004, 15, S628-S633.	2.6	27
142	Monolithic integration of mass sensing nano-cantilevers with CMOS circuitry. Sensors and Actuators A: Physical, 2003, 105, 311-319.	4.1	43
143	Modeling the Thermal Actuation in a Thermo-Pneumatic Micropump. Journal of Electronic Packaging, Transactions of the ASME, 2003, 125, 527-530.	1.8	5
144	Adapting MCM-D technology to a piezoresistive accelerometer packaging. Journal of Micromechanics and Microengineering, 2003, 13, S41-S44.	2.6	3

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145	SOI-silicon as structural layer for NEMS applications. , 2003, , .		4
146	Development and Characterization of Co-Ni Alloys for Microsystems Applications. Journal of the Electrochemical Society, 2002, 149, C201.	2.9	40
147	Protection of MOS capacitors during anodic bonding. Journal of Micromechanics and Microengineering, 2002, 12, 361-367.	2.6	9
148	Electrodeposited Co-Ni alloys for MEMS. Journal of Micromechanics and Microengineering, 2002, 12, 400-405.	2.6	52
149	Piezoresistive accelerometers for MCM package. Journal of Microelectromechanical Systems, 2002, 11, 794-801.	2.5	41
150	Electrochemical deposition of metal layers and structures for Si-based microsystems. Sensors and Actuators A: Physical, 2002, 99, 41-44.	4.1	6
151	Electromechanical model of a resonating nano-cantilever-based sensor for high-resolution and high-sensitivity mass detection. Nanotechnology, 2001, 12, 100-104.	2.6	106
152	Ion beam synthesis of n-type doped SiC layers. Applied Surface Science, 2001, 184, 367-371.	6.1	2
153	Growth and characterization of shape memory alloy thin films for Si microactuator technologies. Journal of Materials Science: Materials in Electronics, 2001, 12, 323-326.	2.2	6
154	Structural and Electrical Characterization of Ion Beam Synthesized and n-Doped SiC Layers. Materials Science Forum, 2001, 353-356, 591-594.	0.3	0
155	Differential injection analysis based on backside-contacted ISFETs. , 2001, , .		1
156	Structural and Micromechanical Assessment of Electrochemically Grown Metal Layers for Si Magnetic Microactuators. Materials Research Society Symposia Proceedings, 2000, 657, 421.	0.1	1
157	Twin-mass accelerometer optimization to reduce the package stresses. Sensors and Actuators A: Physical, 2000, 80, 199-207.	4.1	22
158	The use of ferrofluids in micromechanics. Sensors and Actuators A: Physical, 2000, 84, 176-180.	4.1	62
159	Epitaxial Growth of $\hat{1}^2$ -SiC on Ion-Beam Synthesized $\hat{1}^2$ -SiC: Structural Characterization. Materials Science Forum, 2000, 338-342, 309-312.	0.3	3
160	Ion beam synthesis of polycrystalline SiC on SiO ₂ structures for MEMS applications. Journal of Micromechanics and Microengineering, 2000, 10, 152-156.	2.6	9
161	Test microstructures for measurement of SiC thin film mechanical properties. Journal of Micromechanics and Microengineering, 1999, 9, 190-193.	2.6	13
162	Determination of micromechanical properties of thin films by beam bending measurements with an atomic force microscope. Sensors and Actuators A: Physical, 1999, 74, 134-138.	4.1	55

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163	Micromachined optical fiber current sensor. Applied Optics, 1999, 38, 5298.	2.1	8
164	Cathodic Debond of Anodically Bonded Silicon to Glass Wafers. Electrochemical and Solid-State Letters, 1999, 3, 392.	2.2	9
165	<title>Doping and structural properties for the phosphorous-doped polysilicon layers used for micromechanical applications</title>. , 1999, , .		0
166	<title>Mechanical stress in polysilicon layers and evaluation by a new procedure</title>. , 1999, 3893, 368.		0
167	New bulk accelerometer for triaxial detection. Sensors and Actuators A: Physical, 1998, 66, 105-108.	4.1	25
168	Effect of silicon oxide, silicon nitride and polysilicon layers on the electrostatic pressure during anodic bonding. Sensors and Actuators A: Physical, 1998, 67, 181-184.	4.1	24
169	Simple technology for bulk accelerometer based on bond and etch back silicon on insulator wafers. Sensors and Actuators A: Physical, 1998, 68, 299-302.	4.1	22
170	<title>Diffusion-induced dislocations in highly boron-doped silicon layers used for bulk micromachining applications</title>. , 1998, 3511, 88.		2
171	Analytical Modeling of the Gold Diffusion Induced Modification of the Forward Current through P-N Silicon Junctions. Solid State Phenomena, 1997, 57-58, 525-0.	0.3	0
172	Nondestructive Anodic Bonding Test. Journal of the Electrochemical Society, 1997, 144, L108-L110.	2.9	12
173	Design of a modular micropump based on anodic bonding. Journal of Micromechanics and Microengineering, 1997, 7, 179-182.	2.6	61
174	Non-destructive in situ test for anodic bonding. Sensors and Actuators A: Physical, 1997, 60, 176-180.	4.1	16
175	New FET accelerometer based on surface micromachining. Sensors and Actuators A: Physical, 1997, 61, 342-345.	4.1	14
176	Resonant silicon accelerometers in bulk micromachining technology-an approach. Journal of Microelectromechanical Systems, 1996, 5, 122-130.	2.5	42
177	High-performance piezoresistive pressure sensors for biomedical applications using very thin structured membranes. Measurement Science and Technology, 1996, 7, 1195-1203.	2.6	62
178	Electrostatically controlled multi-purpose torsional structures obtained on monocrystalline silicon. Journal of Micromechanics and Microengineering, 1996, 6, 103-104.	2.6	1
179	A new process for releasing micromechanical structures in surface micromachining. Journal of Micromechanics and Microengineering, 1996, 6, 36-39.	2.6	12
180	Surface micromachining technology applied to the fabrication of a FET pressure sensor. Journal of Micromechanics and Microengineering, 1996, 6, 80-83.	2.6	23

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181	Application of simple thioether ionophores to silver ion-selective CHEMFETs. Sensors and Actuators B: Chemical, 1995, 27, 321-324.	7.8	13
182	Application of nickel electroless plating to the fabrication of low-cost backside contact ISFETs. Sensors and Actuators B: Chemical, 1995, 27, 336-340.	7.8	14
183	A technology for the monolithic fabrication of a pressure sensor and related circuitry. Sensors and Actuators A: Physical, 1995, 46, 133-136.	4.1	9
184	New technology for easy and fully IC-compatible fabrication of backside-contacted ISFETs. Sensors and Actuators B: Chemical, 1995, 24, 228-231.	7.8	12
185	Stress measurement by microRaman spectroscopy of polycrystalline silicon structures. Journal of Micromechanics and Microengineering, 1995, 5, 132-135.	2.6	34
186	Fabrication and characterization of a twin-mass accelerometer. Sensors and Actuators A: Physical, 1994, 43, 115-119.	4.1	17
187	Anisotropic etch-stop properties of nitrogen-implanted silicon. Sensors and Actuators A: Physical, 1994, 45, 219-225.	4.1	4
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